



IFW

**PATENT APPLICATION**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Atsushi SANO et al.

Group Art Unit: 2812

Application No.: 10/574,571

Examiner: S. NIKMANESH

Filed: April 28, 2006

Docket No.: 127570

For: MANUFACTURING METHOD OF SEMICONDUCTOR DEVICE AND SUBSTRATE  
PROCESSING APPARATUS

**AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In reply to the October 15, 2008 Office Action, please consider the following:

**Amendments to the Claims** as reflected in the listing of claims;

**Remarks.**